

Nano4me.org Video Download

ESC 212: Basic Nanotechnology Processes

Unit 2: An Introduction to Uses of Plasmas in Processing



Lecture 3

Length: 48:37

This video will cover:

- Additive Plasma Processes
- Plasma Enhanced Chemical Vapor Deposition (PECVD)
- Plasma Enhanced Atomic Layer Deposition (PEALD)
- Application of PECVD and PEALD

Thank You For Watching!

What did you think? [Email](#) Bob Ehrmann with your feedback.

Funded, in part, by a grant from the National Science Foundation. DUE 1205105